

Notice of References Cited

Application/Control No. 09/022,834	Reexamination	Applicant(s)/Patent Under Reexamination DEGENDT ET AL.	
Examiner	Art Unit		
Shamim Ahmed	1746	Page 1 of 1	

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Class	ification
	Α	US-5466389	11-1995	llardi et al	252	156
	В	US-3871929	03-1975	Schevey et al	216	83
	С	US-			-	
	D	US-			 	
	Ε	US-			1	
	F	US-			 	
	G	US-				
	Н	US-			 	
	ı	US-	-			
	J	US-				
	к	US-				
	L	US-				
	М	US-				

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification	
	N						
	0						
	Р			-			
	Q						
	R						
	s						
	Т						· · · · · · · · · · · · · · · · · · ·

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Kern, Werner, "Hand Book of Semiconductor Wafer Cleaning Technology", 1993, p.599-601
	٧	
	w	
	х	
* ^	E 44.	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).) Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.